

	Sep.5(Sun)	Sep.6 ( Mon )							Sep.7 ( Tue )							Sep.8 ( Wed )							Sep.9 ( Thu )			
	MO Hall (Room A)	Room B	Room C	Room D	Room E	Room F	3F Lobby	1F Lobby	MO Hall (Room A)	Room B	Room C	Room D	Room E	Room F	3F Lobby	1F Lobby	MO Hall (Room A)	Room B	Room C	Room D	Room E	Room F	3F Lobby	1F Lobby	Technical Visit	
8:45																										
9:00		MO Hall OPEN																					Tour1 Start	Tour2 Start		
9:30		OPENING Ceremony							Plenary4 Albert Weckenmann							B-5 Novel Method for Medical and Biological Measurement							Bus	Bus		
10:00		Plenary1 Tilo Pfeifer							Plenary5 Ramanamorthy Balakrishnan							C-6 Machine Vision and Image Processing							Break			
10:30		Break							Break							D-5 Intelligent Micro and Nano Metrology (2)							Industrial Exhibition			
11:00		Break							A-3 Best Paper Award							E-3 CMM Metrology (2)							Information Desk			
11:30		Plenary2 Richard Leach							B-3 Optical Measurement for Geometrical Quantity Evaluation (2)							F-3 Uncertainty Evaluation and Traceability (2)							Technical visit Panasonic		Technical visit Shimadzu	
12:00		Plenary3 Kiyoshi Takamasu							C-3 Pre- In- Post process measurement							D-6 Pre- In- Post process measurement (2)							Break			
12:30		Lunch							Registration							E-6 Geometrical Product Specification and Form Test							Closing Ceremony			
13:00		Lunch							Lunch							F-6 Intelligent Measurement Algorithm and Simulation(2)							Lunch		Lunch	
13:30		Lunch							Lunch							Industrial Exhibition							Bus		Bus	
14:00		Registration							C-1 Optical Measurement for Geometrical Quantity Evaluation (1)							Poster Session Industrial Exhibition							Registration			
14:30		B-1 3-D Surface Texture and its Micro Characteristics							D-1 Advanced Optoelectronic Sensors and Instrument(1)							F-1 Macrogeometri c Features and Uncertainty Evaluation							Nisshin Instant Noodle Museum		Asahi Beer Sulta Factory	
15:00		Keynote1 Yuri Chugui							E-1 Ultra Precision Length Measurement							Coffee Break 30 minutes							Registration and Information Desk			
15:30		Coffee Break 30 minutes							Industrial Exhibition							Keynote6 Ryszard Jablonski							Registration and Information Desk			
16:00		B-2 Gear Metrology							C-2 MEMS/MOEMS application in Measurement field							D-4 Optical Measurement for Geometrical Quantity Evaluation (3)							Registration and Information Desk			
16:30		Keynote2 Hideki Ina							D-2 Advanced Optoelectronic Sensors and Instrument(2)							E-4 CMM Metrology (3)							Registration and Information Desk			
17:00		Keynote4 Sanwat Zahwi							E-2 CMM Metrology (1)							F-4 Tolerance, Testing, Test Planning							Registration and Information Desk			
17:30	Welcome Reception								F-2 Uncertainty Evaluation and Traceability (1)							Industrial Exhibition							Registration and Information Desk			
									Bus Convention center to the Sanri Hankyu hotel																	
									Banquet																	